



AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITED PROSECUTION - GROUP ART UNIT 1762

03500.016291.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
:)
RYUJI BIRO, ET AL.)
:)
Application No.: 10/098,569)
:)
Filed: March 18, 2002)
:)
For: VACUUM DEPOSITION)
SYSTEM AND THIN-FILM :
DEPOSITION PROCESS) June 30, 2004

Examiner: Marianne L. Padgett

Group Art Unit: 1762

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

a) Introductory Comments

In response to the final Office Action dated April 1, 2004, kindly amend the
subject application under 37 C.F.R. § 1.116 as follows:

IFW
AF/1762

Entered by
RCE
8/9/04
RCE

Do not enter - Mr. Padgett 7/26/04